

**INFORMATION DISCLOSURE
STATEMENT BY APPLICANT**

(Use as many sheets as necessary)

Sheet	1	of	1	Attorney Docket Number	02386.0105
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Complete if Known

Application Number	10/581,497
Filing Date	June 2, 2006
First Named Inventor	Babak HEIDARI
Art Unit	1791
Examiner Name	Stephen J. SOLLENBERGER

U.S. PATENTS AND PUBLISHED U.S. PATENT APPLICATIONS

Examiner Initials	Cite No. ¹	Document Number	Issue or Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number-Kind Code ² (if known)			
		US 4,844,947	07/04/1989	Kasner et al.	
		US 6,027,630	02/22/2000	Cohen	
		US 6,284,345	09/04/2001	Ruoff	
		US 7,374,864	05/20/2008	Guo et al.	
		US 2004/0079730	04/29/2004	Ahrens et al.	

Note: Submission of copies of U.S. Patents and published U.S. Patent Applications is not required.**FOREIGN PATENT DOCUMENTS**

Examiner Initials	Cite No. ¹	Foreign Patent Document	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	Translation ⁶
		Country Code ³ Number ⁴ Kind Code ⁵ (if known)				
		JP 2000-194142	07-14-2000	Fujitsu Ltd		Abstract

NONPATENT LITERATURE DOCUMENTS

Examiner Initials	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	Translation ⁶
		WISSEN et al., "UV CURING OF RESISTS FOR WARM EMBOSSING", Elsevier B.V., Microelectronic Engineering, Vol. 73-74, pp. 184-187, (2004).	
		REANO et al., "STABILITY OF FUNCTIONAL POLYMERS AFTER PLASTICIZER-ASSISTED IMPRINT LITHOGRAPHY", Journal of Vacuum Science & Technology, American Vacuum Society, Vol. 22, No. 6, pp. 3294-3299, (2004).	
		BENDER et al., "FABRICATION OF NANOSTRUCTURES USING A UV-BASED IMPRINT TECHNIQUE", Elsevier B.V., Microelectronic Engineering, Vol. 53, pp. 233-236, (2000).	

Examiner Signature	Date Considered
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EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.